



RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

PATENT APPLICATION
Docket No. 5484-085
Client No. PX1353-US/SSM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): Jong-Kill Lim Confirmation No. 7239
Serial No.: 10/021,608 Examiner: Hung Nguyen
Filing Date: December 11, 2001 Group Art Unit: 2851
Title: EXPOSURE CONTROL APPARATUS IN A LITHOGRAPHY
SYSTEM AND METHOD THEREOF

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Responsive to the Final Office Action, Paper No. 101003, dated October 20, 2003,
please amend the application as follows.

Amendments to the Claims are reflected in the listing of claims 1-11 which begins
on page 2 of this paper.

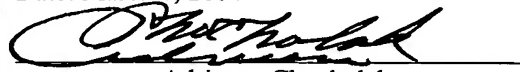
Remarks/Arguments begin on page 5 of this paper.

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Adrienne Chocholak